

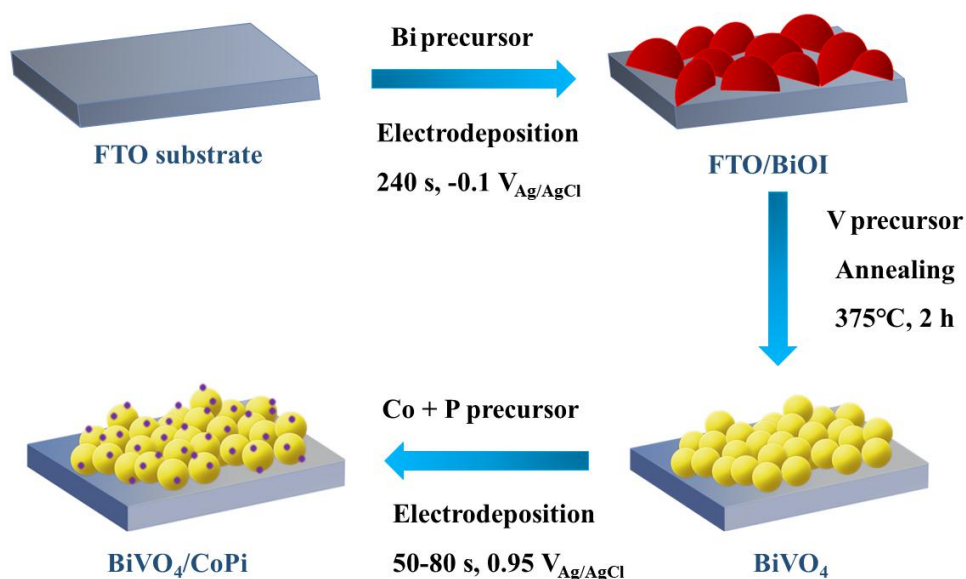
**A highly enhanced photoelectrochemical performance of BiVO<sub>4</sub> photoanodes modified with CoPi groups by increasing energy band bending, accelerating hole separation and improving water oxidation kinetics**

Wanqing Fang,<sup>a</sup> Ai Qin,<sup>a</sup> Yimin Lin,<sup>a</sup> Rongzi Xu,<sup>a</sup> and Li Fu<sup>\*a</sup>

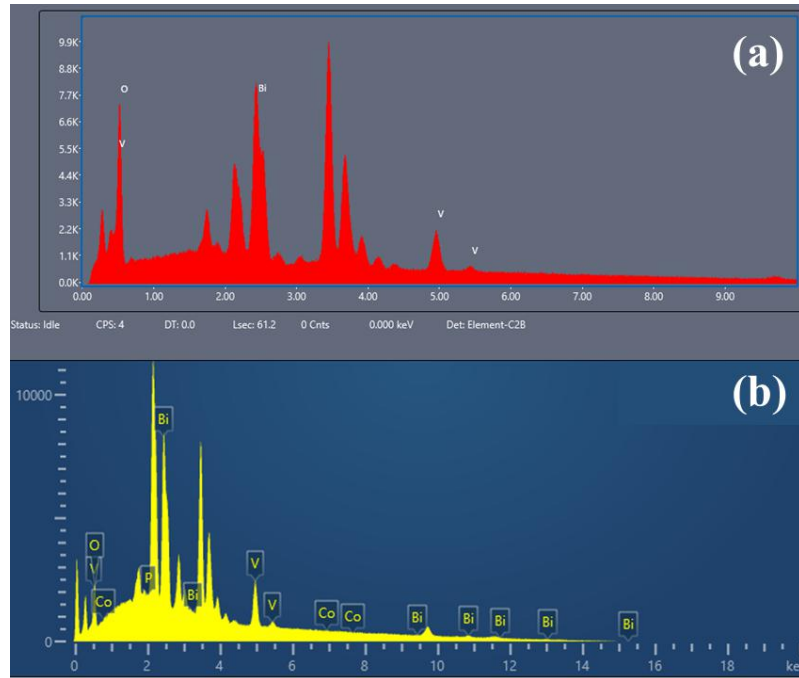
<sup>a</sup> Fujian Provincial Key Laboratory of Advanced Materials Oriented Chemical Engineering, Fujian Provincial Key Laboratory of Polymer Materials, College of Chemistry and Material Science, Fujian Normal University, Cangshan Campus, No.8 Shangsang Road, Fuzhou, Fujian 350007, China.

**\*Corresponding author**

E-mail address: wodimeige@163.com



**Figure S1** Synthetic process of bare BiVO<sub>4</sub> and BiVO<sub>4</sub>/CoPi photoanodes.



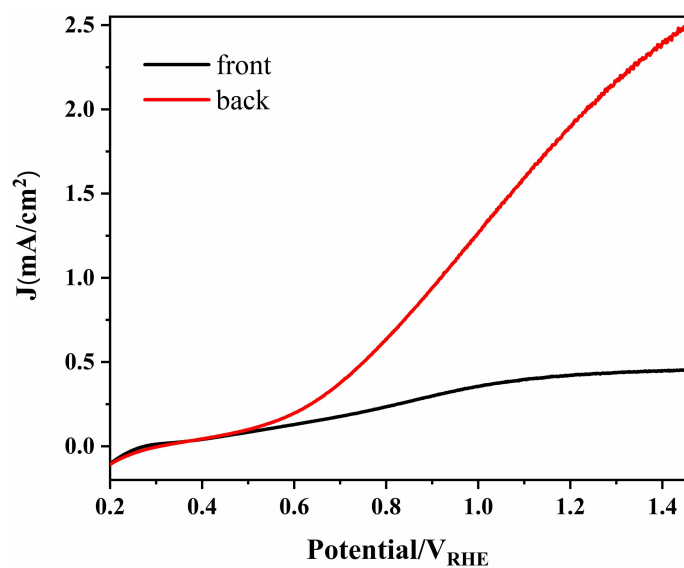
**Figure S2** EDX scanning spectra of (a) BiVO<sub>4</sub> and (b) BiVO<sub>4</sub>/CoPi.

**Table S1** The content of the corresponding elements in BiVO<sub>4</sub> and BiVO<sub>4</sub>/CoPi from the EDX scanning spectra.

| Element   | wt%               |                         | at%               |                         |
|-----------|-------------------|-------------------------|-------------------|-------------------------|
|           | BiVO <sub>4</sub> | BiVO <sub>4</sub> /CoPi | BiVO <sub>4</sub> | BiVO <sub>4</sub> /CoPi |
| <b>Bi</b> | 62.86             | 71.92                   | 16.82             | 23.94                   |
| <b>V</b>  | 19.44             | 14.98                   | 21.33             | 20.46                   |
| <b>O</b>  | 17.70             | 12.67                   | 61.85             | 55.10                   |
| <b>Co</b> | 0                 | 0.43                    | 0                 | 0.50                    |

**Table S2** The content of each element in BiVO<sub>4</sub> and BiVO<sub>4</sub>/CoPi from the XPS spectra of overall survey.

| Sample       | BiVO <sub>4</sub> | BiVO <sub>4</sub> /CoPi |
|--------------|-------------------|-------------------------|
| Name         | Atomic %          | Atomic %                |
| <b>Bi 4f</b> | 16.62             | 13.58                   |
| <b>V 2p</b>  | 25.13             | 23.23                   |
| <b>O 1s</b>  | 59.25             | 54.75                   |
| <b>Co 2p</b> | 0                 | 2.98                    |
| <b>P 2p</b>  | 0                 | 5.45                    |



**Figure S3** LSV curves of BiVO<sub>4</sub> photoanode front and back irradiation.

**Table S3** Comparisons of photoelectrochemical performance of reported previously BiVO<sub>4</sub>-based photoanode with our results.

| Photoelectrode                                       | Fabrication process       | Test condition                        | Bias   | Photocurrent density(mA/cm <sup>2</sup> ) |         |      | Ref.      |
|--|---------------------------|---------------------------------------|--------|---|---------|------|-----------|
|  |                           |                                       |        | bare                                      | Treated | Fold |           |
| BiVO <sub>4</sub> /CoPi                              | electrodeposition process | 2 M NaBi                              | 1.23 V | 1.81                                      | 5.87    | 3.24 | This work |
| Co:BiVO <sub>4</sub>                                 | spin coating              | 0.5 M Na <sub>2</sub> SO <sub>4</sub> | 1.23 V | 0.22                                      | 0.46    | 2.09 | [1]       |
| BiVO <sub>4</sub> /Co(CO <sub>3</sub> ) <sub>x</sub> | hydrothermal process      | 1 M NaOH                              | 1.23 V | 2.20                                      | 5.00    | 2.27 | [2]       |
| OH <sub>y</sub>                                      |                           |                                       |        |   |         |      |           |
| WO <sub>3</sub> /BiVO <sub>4</sub>                   | sol - gel process         | 0.1 M KPi                             | 1.23 V | 0.53                                      | 2.50    | 4.72 | [3]       |
| Li:BiVO <sub>4</sub>                                 | pulsed laser deposition   | 0.1 M PBS<br>(pH=7)                   | 1.23 V | 0.74                                      | 0.87    | 1.18 | [4]       |
| Au:BiVO <sub>4</sub>                                 | solution drop casting     | 0.1 M KOH                             | 1.23 V | 0.07                                      | 0.24    | 3.43 | [5]       |
| BiVO <sub>4</sub> /Co(OH)F                           | solution drop casting     | 0.5 M KPi                             | 1.23 V | 1.45                                      | 3.40    | 2.40 | [6]       |
| SnO <sub>2</sub> @BiVO <sub>4</sub> /Co-             | electrodeposition process | 0.1 M PBS                             | 1.23 V | 0.40                                      | 2.63    | 6.58 | [7]       |

|   |                           |  |        |      |      |      |      |
|---|---------------------------|--|--------|------|------|------|------|
| Pi  |                           | (pH=7)   |        |      |      |      |      |
| Mo:BiVO <sub>4</sub>  | hydrothermal process      | 0.1 M Na <sub>2</sub> SO <sub>4</sub>              | 1.23 V | 1.25 | 1.70 | 1.36 | [8]  |
| MCo <sub>2</sub> O <sub>4</sub> (M=Mn,<br>Zn)/BiVO <sub>4</sub> | spin coating              | 0.5 M KPi  | 1.23 V | 0.80 | 2.80 | 3.5  | [9]  |
| Mo,W:BiVO <sub>4</sub> /PC                                      | solution drop casting     | 0.1 M Na <sub>2</sub> SO <sub>4</sub>              | 1.23 V | 0.4  | 2.50 | 6.25 | [10] |
| α -Fe <sub>2</sub> O <sub>3</sub>                               |                           |  |        |      |      |      |      |
| BiVO <sub>4</sub> /CoSi   | PEPD                      | 0.5 M K <sub>2</sub> B <sub>4</sub> O <sub>7</sub> | 1.23 V | 1.7  | 5.0  | 2.9  | [11] |
|   |                           | (pH=9.5)   |        |      |      |      |      |
| F-BiVO <sub>4</sub> @NiFe-L                                     | electrodeposition process | 0.1 M PBS  | 1.23 V | 0.45 | 2.67 | 6.0  | [12] |
| DH  |                           | (pH=7)   |        |      |      |      |      |
| CoPi/PANI/<br>BiVO <sub>4</sub>                                 | PEPD                      | 0.5 M KH <sub>2</sub> PO <sub>4</sub>              | 1.23 V | 0.98 | 4.05 | 4.13 | [13] |
| BiVO <sub>4</sub> -N/C-CoPO                                     | dipping process           | 0.5 M PBS  | 1.23 V | 0.61 | 3.30 | 5.4  | [14] |
| M   |                           |  |        |      |      |      |      |
| CoFeOH/Cu <sub>2</sub> S/<br>BiVO <sub>4</sub>                  | SILAR                     | 0.5 M PBS  | 1.23 V | 2.03 | 3.07 | 1.51 | [15] |
| BiVO <sub>4</sub> /WO <sub>3</sub> NRs                          | hydrothermal process      | 0.5 M KPi  | 1.23 V | 0.40 | 0.64 | 1.60 | [16] |
| BiVO <sub>4</sub> /WO <sub>3</sub> /ITO                         | pulsed laser deposition   | 0.5 M Na <sub>2</sub> SO <sub>4</sub>              | 1.23 V | 0.35 | 0.86 | 2.46 | [17] |
| N-BiVO <sub>4</sub>   | solution drop casting     | 0.1 M KPi  | 1.23 V | 1.6  | 3.3  | 2.1  | [18] |
| CoP/BiVO <sub>4</sub>   | solution drop casting     | KBi (pH=9)   | 1.23 V | 2.0  | 4.1  | 2.05 | [19] |
| R-BiVO <sub>4</sub>   | dipping process           | 0.2M KPi   | 1.23 V | 2.24 | 3.18 | 2.21 | [20] |
| Mo: BiVO <sub>4</sub> /   | spin coating              | 0.1 M PBS  | 1.23 V | 0.03 | 1.1  | 36.7 | [21] |

CoOOH

BiVO<sub>4</sub>/Co-LaFeO electrodeposition process 0.5 M KPi 1.23 V 0.85 3.40 4 [22]

3

CuTCPP/GO/ dipping process 0.5 M PBS 1.23 V 1.25 5.0 4 [23]

BiVO<sub>4</sub> (pH=9)

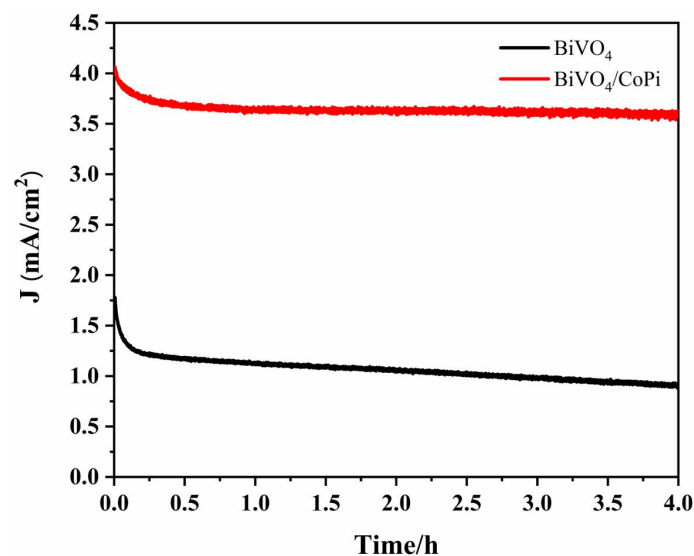
FeOOH/Au/ electrodeposition process 0.1 M Na<sub>2</sub>SO<sub>4</sub> 1.23 V 1.19 4.64 3.74 [24]

BiVO<sub>4</sub>

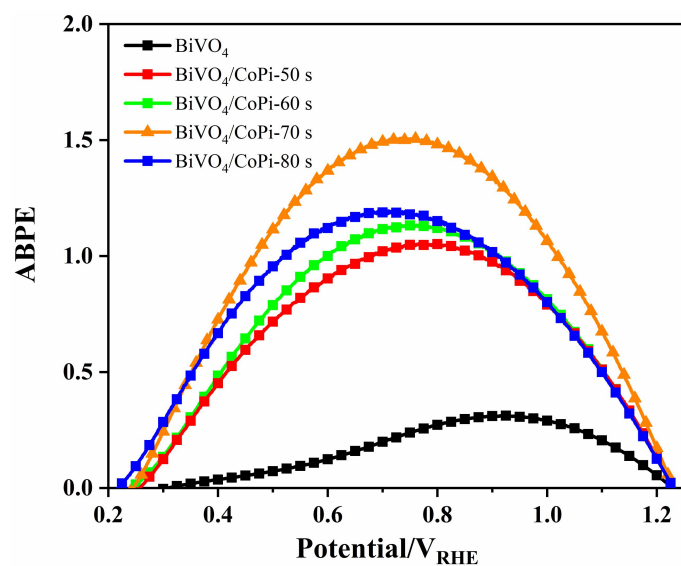
Co-Ci/Mo: BiVO<sub>4</sub> PEPD 0.5 M Na<sub>2</sub>SO<sub>4</sub> 1.23 V 0.82 3.95 4.8 [25]

Unless otherwise specified, all photoelectrochemical tests were carried out under simulated 1 sun (AM 1.5 G, 100mW · cm<sup>-2</sup>) illumination and all biases were converted to RHE (V<sub>RHE</sub>). The fabrication process represents the modification way of bare BiVO<sub>4</sub>.

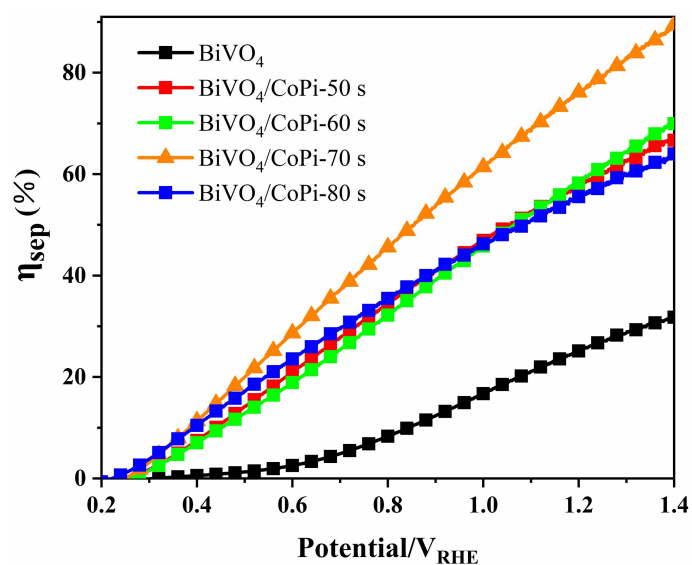
Involved abbreviations: PC, partially covered; PEPD, photoelectrophoretic deposition; PBS, phosphate buffer saline; PANI, polyaniline; SILAR, successive ionic layer adsorption; NRs, nanorods; R-BiVO<sub>4</sub>, the photoassisted self-reduction of the BiVO<sub>4</sub>; Co-Ci, carbon-based cobalt.



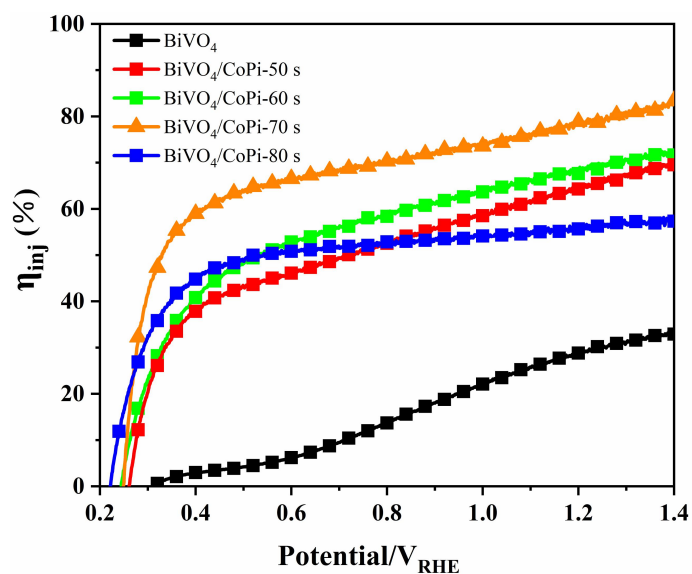
**Figure S4** Stability test of 4 h for BiVO<sub>4</sub> and BiVO<sub>4</sub>/CoPi films at 1.23 V<sub>RHE</sub> under AM 1.5G (100 mW cm<sup>-2</sup>) illumination in borate buffer.



**Figure S5** ABPE of BiVO<sub>4</sub> and various deposition times (50-80 s) of BiVO<sub>4</sub>/CoPi films with a voltage in the range of 0.2~1.23 V<sub>RHE</sub>.



**Figure S6** η<sub>sep</sub> of BiVO<sub>4</sub> and various deposition times (50-80 s) of BiVO<sub>4</sub>/CoPi films with a voltage in the range of 0.2~1.4 V<sub>RHE</sub>.



**Figure S7**  $\eta_{inj}$  of  $\text{BiVO}_4$  and various deposition times (50-80 s) of  $\text{BiVO}_4/\text{CoPi}$  films with a voltage in the range of 0.2~1.4  $V_{\text{RHE}}$ .

**Table S4** Values of the elements in equivalent circuit fitted in the Nyquist plots of Fig. 8a.

| sample                      | $R_s/\Omega$ (error/%) | $R_{ct}/\Omega$ (error/%) | CPE/F (error/%)               |
|-----------------------------|------------------------|---------------------------|-------------------------------|
| $\text{BiVO}_4$             | 58.65 (0.78)           | 194.6 (1.11)              | $7.49 \times 10^{-5}$ (5.16)  |
| $\text{BiVO}_4/\text{CoPi}$ | 51.44 (1.27)           | 122.0 (3.12)              | $16.32 \times 10^{-5}$ (3.76) |

#### Reference:

- 1 P.S. Shinde, X. Peng, J. Wang, Y. Ma, L.E. McNamara, N.I. Hammer, A. Gupta, S. Pan, *ACS Appl. Energy Mater.*, 2018, **1**, 2283-2294.
- 2 L. Wu, L. Wang, J. Zhu, M. Sun, X. Liu, P. Schmuki, J. Zhang, *J. Mater. Chem. A*, 2020, **8**, 2563-2570.
- 3 J. Feng, H. Huang, W. Guo, X. Xu, Y. Yao, Z. Yu, Z. Li, Z. Zou, *Chem. Eng. J.*, 2021, **417**, 128095-128105.
- 4 C. Zhou, Z. Sanders-Bellis, T.J. Smart, W. Zhang, L. Zhang, Y. Ping, M. Liu, *Chem. Mater.*, 2020, **32**, 6401-6409.
- 5 C. Venkata Reddy, I. Neelakanta Reddy, K. Ravindranadh, K. Raghava Reddy, J. Shim, B. Cheolho, *Appl. Surf. Sci.*, 2021, **545**, 149030-149039.
- 6 S. Alam, T.K. Sahu, M. Qureshi, *ACS Sustain. Chem. Eng.*, 2021, **9**, 5155-5165.
- 7 J. Liu, J. Li, M. Shao, M. Wei, *J. Mater. Chem. A*, 2019, **7**, 6327-6336.
- 8 M. Huang, J. Bian, W. Xiong, C. Huang, R. Zhang, *J. Mater. Chem. A*, 2018, **6**, 3602-3609.
- 9 D. Xu, T. Xia, H. Xu, W. Fan, W. Shi, *Chem. Eng. J.*, 2020, **392**, 124838-124846.
- 10 J. Li, J. Li, H. Yuan, W. Zhang, Z. Jiao, X. Song Zhao, *Chem. Eng. J.*, 2020, **398**, 125662-125670.
- 11 Q. Sun, T. Cheng, Z. Liu, L. Qi, *Appl. Catal. B-Environ.*, 2020, **277**, 119189-119196.
- 12 J. Liu, J. Li, Y. Li, J. Guo, S.-M. Xu, R. Zhang, M. Shao, *Appl. Catal. B-Environ.*, 2020, **278**,

119268-119277.

- 13 M. Zhao, T. Chen, B. He, X. Hu, J. Huang, P. Yi, Y. Wang, Y. Chen, Z. Li, X. Liu, *J. Mater. Chem. A*, 2020, **8**, 15976-15983.
- 14 K. Fan, H. Chen, B. He, J. Yu, *Chem. Eng. J.*, 2020, **392**, 123744-123753.
- 15 S.-S. Zhu, Y. Zhang, Y. Zou, S.-Y. Guo, H. Liu, J.-J. Wang, A. Braun, *J. Phys. Chem. C*, 2021, **125**, 15890-15898.
- 16 J.-H. Kim, D.H. Kim, J.W. Yoon, Z. Dai, J.-H. Lee, *ACS Appl. Energy Mater.*, 2019, **2**, 4535-4543.
- 17 P.-W. Shao, Y.-S. Siao, Y.-H. Lai, P.-Y. Hsieh, C.-W. Tsao, Y.-J. Lu, Y.-C. Chen, Y.-J. Hs-u, Y.-H. Chu, *ACS Appl. Mater. Interf.*, 2021, **13**, 21186-21193.
- 18 T. Eo, T. Katsuki, M.R. Berber, Z.N. Zahran, E.A. Mohamed, Y. Tsubonouchi, A.M. Alen-ad, N.A. Althubiti, M. Yagi, *ACS Appl. Energy Mater.*, 2021, **4**, 2983-2989.
- 19 T. Tran-Phu, Z. Fusco, I. Di Bernardo, J. Lipton-Duffin, C.Y. Toe, R. Daiyan, T. Gengenbach, C.-H. Lin, R. Bo, H.T. Nguyen, G.M.J. Barca, T. Wu, H. Chen, R. Amal, *Chem. Mater.*, 2021, **33**, 3553-3565.
- 20 X. Yin, J. Li, L. Du, F. Zhan, K. Kawashima, W. Li, W. Qiu, Y. Liu, X. Yang, K. Wang, Y. Ning, C.B. Mullins, *ACS Appl. Energy Mater.*, 2020, **3**, 4403-4410.
- 21 R. Yalavarthi, R. Zbořil, P. Schmuki, A. Naldoni, Š. Kment, *J. Power Sources*, 2018, **6**, 3602-3609.
- 22 Y. Gao, G. Yang, Y. Dai, X. Li, J. Gao, N. Li, P. Qiu, L. Ge, *ACS Appl. Mater. Interf.*, 2020, **12**, 17364-17375.
- 23 C. Xu, W. Sun, Y. Dong, C. Dong, Q. Hu, B. Ma, Y. Ding, *J. Mater. Chem. A*, 2020, **8**, 4062-4072.
- 24 H. Geng, P. Ying, Y. Zhao, X. Gu, *Int. J. Hydrogen Energy*, 2021, **46**, 35280-35289.
- 25 S. Kumar, A.K. Satpati, *Electrochim. Acta*, 2021, **368**, 137565-137579.